Swept-Angle Synthetic Wavelength Interferometry
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Abstract

We present a new imaging technique, swept-angle synthetic wavelength interferometry, for full-field micron-scale 3D sensing. As in conventional synthetic wavelength interferometry, our technique uses light consisting of two narrowly-separated optical wavelengths, resulting in per-pixel interferometric measurements whose phase encodes scene depth. Our technique additionally uses a new type of light source that, by emulating spatially-incoherent illumination, makes interferometric measurements insensitive to aberrations and (sub)surface scattering, effects that corrupt phase measurements. The resulting technique combines the robustness to such corruptions of scanning interferometric setups, with the speed of full-field interferometric setups. Overall, our technique can recover full-frame depth at a lateral and axial resolution of 5 µm, at frame rates of 5 Hz, even under strong ambient light. We build an experimental prototype, and use it to demonstrate these capabilities by scanning a variety of objects, including objects representative of applications in inspection and fabrication, and objects that contain challenging light scattering effects.

1. Introduction

Depth sensing is among the core problems of computer vision and computational imaging, with widespread applications in medicine, industry, and robotics. An array of techniques is available for acquiring depth maps of three-dimensional (3D) scenes at different scales. In particular, micrometer-resolution depth sensing, our focus in this paper, is important in biomedical imaging because biological features are often micron-scale, industrial fabrication and inspection of critical parts that must conform to their specifications (Figure 1), and robotics to handle fine objects.

Active illumination depth sensing techniques such as lidar, structured light, and correlation time-of-flight (ToF) cannot provide micrometer axial resolution. Instead, we focus on interferometric techniques that can achieve such resolutions. The operational principles and characteristics of interferometric techniques vary, depending on the type of active illumination and optical configurations they use.

The choice of illumination spectrum leads to techniques such as optical coherence tomography (OCT), which uses broadband illumination, and phase-shifting interferometry (PSI), which uses monochromatic illumination. We consider synthetic wavelength interferometry (SWI), which operates between these two extremes: By using illumination consisting of two narrowly-separated optical wavelengths, SWI provides a controllable trade-off between the large unambiguous depth range of OCT, and the large axial resolution of PSI. SWI can achieve micrometer resolution at depth ranges in the order of hundreds of micrometers.

The choice of optical configuration results in full-field versus scanning implementations, which offer different trade-offs. Full-field implementations acquire entire 2D depth maps, offering simultaneously fast operation and pixel-level lateral resolutions. However, full-field implementations are very sensitive to effects that corrupt depth estimation, such as imperfections in free-space optics (e.g., lens aberrations) and indirect illumination (e.g., subsurface scattering). By contrast, scanning implementations use beam steering to sequentially scan points in a scene and produce a 2D depth map. Scanning implementations offer robustness to depth corruption effects, through the use of fiber optics to reduce aberrations, and co-axial illumination and sensing to eliminate most indirect illumination. However, scanning makes acquiring depth maps with pixel-level lateral resolution and megapixel sizes impractically slow.

We develop a 3D sensing technique, swept-angle synthetic wavelength interferometry, that combines the complementary advantages of full-field and scanning implementations. We draw inspiration from previous work showing...
that the use of *spatially-incoherent illumination* in full-field interferometry mitigates aberration and indirect illumination effects. We design a light source that emulates spatial incoherence, by scanning *within exposure* a dichromatic point source at the focal plane of the illumination lens, effectively sweeping the illumination angle—hence *swept-angle*. We combine this light source with full-field SWI, resulting in a 3D sensing technique with the following performance characteristics: 5 Hz full-frame 2 Mpixel acquisition; 5 µm lateral and axial resolution; range and resolution tunability; and robustness to aberrations, ambient illumination, and indirect illumination. We build an experimental prototype, and use it to demonstrate these capabilities, as in Figure 2. We provide setup details, reconstruction code, and data in the supplement and project website.\footnote{https://imaging.cs.cmu.edu/swept_angle_swi}

**Potential impact.** Swept-angle SWI is relevant for critical applications, including industrial fabrication and inspection. In industrial fabrication, swept-angle SWI can be used to provide feedback during additive and subtractive manufacturing processes [67]. In industrial inspection, swept-angle SWI can be used to examine newly-fabricated or used-in-place critical parts and ensure they comply with operational specifications. Swept-angle SWI, uniquely among 3D scanning techniques, offers a combination of features that are critical for both applications: First, high acquisition speed, which is necessary to avoid slowing down the manufacturing process, and to perform inspection efficiently. Second, micrometer lateral and axial resolution, which is necessary to detect critical defects. Third, robustness to aberrations and indirect illumination, which is necessary because of the materials used for fabrication, which often have strong subsurface scattering. Figure 1 showcases results representative of these applications: We scan a fuselage section from a Boeing aircraft, to detect critical defects such as scratches and bumps from collisions, at axial and lateral scales of a couple dozen micrometers. We also scan a coin pattern 3D-printed by a commercial material printer on a translucent material.

### 2. Related work

**Depth sensing.** There are many technologies for acquiring depth in computer vision. Passive techniques rely on scene appearance under ambient light, and use cues such as stereo [4, 30, 50], (de)focus [21, 31, 69], or shading [28, 34].

![bill scene input image depth surface depth map](image)

**Figure 2. Reconstructing the eagle embossed on a \$20 bill.** The features on the eagle are raised 10 µm off the surface of the bill. The recovered depth shows fine details such as the gaps between the wings reconstructed with high lateral and axial resolution.

### Table 1. Comparison of interferometric depth sensing techniques for millimeter-scale scenes. (f.f.: full-field; ‘scan.’: scanning)

<table>
<thead>
<tr>
<th>method</th>
<th>axial res</th>
<th>lateral res</th>
<th>depth range</th>
<th>acq time</th>
<th>robust</th>
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<tr>
<td>f.f. TD-OCT</td>
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<td>✓</td>
<td>✓</td>
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<tr>
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<td>✓</td>
<td>✗</td>
</tr>
<tr>
<td>f.f. SWI</td>
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<td>✓</td>
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<td>scan. SWI</td>
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<td>✗</td>
</tr>
<tr>
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Active techniques inject controlled light in the scene, to overcome issues such as lack of texture and limited resolution. These include structured light [6, 24, 56, 65], impulse ToF [2, 19, 22, 23, 32, 39, 46, 52, 54, 62, 70, 71], and correlation ToF [3, 15, 16, 26, 27, 33, 42, 43, 58, 60, 66]. These techniques cannot easily achieve axial resolutions below hundreds of micrometers, placing them out of scope for applications requiring micrometer resolutions.

**Optical interferometry.** Interferometry is a classic wave-optics technique that measures the correlation, or *interference*, between two or more light beams that have traveled along different paths [29]. Most relevant to our work are three broad classes of interferometric techniques that provide depth sensing capabilities with different advantages and disadvantages, which we summarize in Table 1.

- **Phase-shifting interferometry (PSI)** techniques [9, 37] use single-frequency illumination for nanometer-scale depth sensing. Similar to correlation ToF, they estimate depth by measuring the phase of a sinusoidal waveform. However, whereas correlation ToF uses external modulation to generate megahertz-frequency waveforms, PSI directly uses the terahertz-frequency light waveform. Unfortunately, the unambiguous depth range of PSI is limited to the illumination wavelength, typically around a micrometer.

- **Synthetic wavelength interferometry (SWI)** (or *heterodyne interferometry*) techniques [7, 8, 10, 14, 44, 45] use illumination comprising multiple narrow spectral bands to *synthesize* waveforms at frequencies between the megahertz rates of correlation ToF and terahertz rates of PSI. These techniques allow control of the trade off between unambiguous depth range and resolution, by tuning the frequency of the *synthetic wavelength*. As our technique builds upon SWI, we detail its operational principles in Section 3.
Lastly, optical coherence tomography (OCT) \cite{20,35,41} uses broadband illumination to perform depth sensing analogously to impulse time-of-flight, by processing temporally-resolved (transient) responses. OCT decouples range and resolution, achieving unambiguous depth ranges up to centimeters, at micrometer axial resolutions. This flexibility comes at the cost of increased acquisition time, because of the need for axial (time-domain OCT) or lateral (Fourier-domain and swept-source OCT) scanning \cite{15}.

**Mitigating indirect illumination effects.** In their basic forms, active depth sensing techniques assume the presence of only direct illumination in the scene. *Indirect illumination* effects, such as interreflections and subsurface scattering, confound depth information. For example, in correlation ToF techniques (including PSI and SWI), indirect illumination results in incorrect phase and, thus depth, estimation, an effect also known as *multi-path interference*. Several techniques exist for computationally mitigating indirect illumination effects, using models of multi-bounce transport \cite{18,36,49}, sparse reconstruction \cite{17,38}, multi-wavelength approaches \cite{5}, and neural approaches \cite{48,68}.

Other techniques optically remove indirect illumination by *probing light transport* \cite{57}. Such techniques include epipolar imaging \cite{53,56}, high-spatial-frequency illumination \cite{51,61}, and spatio-temporal coded illumination \cite{1,25,55}. Similar probing capabilities are possible in interferometric systems, by exploiting the spatio-temporal coherence properties of the illumination \cite{20,41}. We adapt these techniques for robust micrometer-scale depth sensing.

### 3. Background on interferometry

**The Michelson interferometer.** Our optical setup is based on the classical Michelson interferometer (Figure 3(c)). The interferometer uses a beam splitter to divide collimated input illumination into two beams: one propagates toward the scene arm, and another propagates toward the reference arm—typically a planar mirror mounted on a translation stage that can vary the mirror’s distance from the beam splitter. After reflection, the two light beams recombine at the beam splitter and propagate toward the sensor.

We denote by \(l\) and \(d(x)\) the distance from the beamsplitter of the reference mirror and the scene point that pixel \(x\) images, respectively. As \(l\) is a controllable parameter, we denote it explicitly. We denote by \(u_r(x,l)\) and \(u_s(x)\) the complex fields arriving at sensor pixel \(x\) from the reference and scene arms respectively. Then, the sensor measures,

\[
I(x,l) = |u_s(x)|^2 + |u_r(x,l)|^2 + 2\text{Re}\{u_s(x)u^*_r(x,l)\}.
\]

The first two terms in Equation (1) are the intensities the sensor would measure if it were observing each of the two arms separately. We call their sum the *interference-free image* \(I\). The third term, which we call *interference*, is the real part of the complex *correlation* \(C\) between the reflected

![Figure 3. Synthetic wavelength interferometry. (a-b) Collimated illumination from a point source emitting at two narrowly-separated wavelengths is injected into a Michelson interferometer. (c) As the reference mirror position \(l\) is scanned, each wavelength contributes to the interference a sinusoid with period equal to its wavelength. (d) The sum of these sinusoids has an envelope that is another sinusoid at a synthetic wavelength peaked at \(l = d(x)\).](image)

**Scene and reference fields.** We elaborate on how to isolate the interference term from Equation (1) in Section 4.

**Synthetic wavelength interferometry.** SWI uses illumination comprising two distinct, but narrowly-separated, wavelengths that are incoherent with each other. We denote these wavelengths as \(\lambda\) and \(\lambda/1+\epsilon\), corresponding to wavenumbers \(\kappa \equiv 2\pi/\lambda\) and \((1+\epsilon)\kappa\), respectively. We assume that this illumination is injected into the interferometer as a collimated beam—for example, created by placing the outputs of two fiber-coupled single-frequency lasers at the focal plane of a lens, as in Figures 3 and 5. Then, we show in the supplement that the correlation \(C(x,l)\) equals

\[
C(x,l) = \exp\left(-2i\kappa (d(x) - l)\right) \left[1 + \exp\left(-2i\epsilon \kappa (d(x) - l)\right)\right].
\]

The interference component of the camera intensity measurements in Equation (1) equals,

\[
\text{Re}(C(x,l)) = 2\sin(\kappa(2\epsilon + \kappa)(d(x) - l))\sin(\kappa\epsilon(d(x) - l))
\approx 2\sin(2\epsilon(d(x) - l))\sin(\kappa\epsilon(d(x) - l)).
\]

The approximation is accurate when \(\epsilon \ll 1\), i.e., when the two wavelengths are close. We observe that, as a function of \(d(x) - l\), the interference is the product of two sinusoids: first, a *carrier sinusoid* with *carrier wavelength* \(\lambda_c \equiv \lambda/2\) and corresponding *carrier wavenumber* \(\kappa_c \equiv 2\lambda;\) second, an *envelope sinusoid* \(E\) with synthetic wavelength \(\lambda_s \equiv \lambda/\epsilon\)
and corresponding synthetic wavenumber $\kappa_s \equiv c\kappa$:
\[ \mathcal{E}(x, l) \equiv \sin(\kappa_s (d(x) - l)). \quad (5) \]
Figure 3(d) visualizes $\text{Re}\{\mathcal{C}(x, l)\}$ and $\mathcal{E}(x, l)$. In practice, we measure only the squared amplitude of the envelope,
\[
|\mathcal{E}(x, l)|^2 = \sin^2(\kappa_s (d(x) - l)) = \frac{1 - \cos(2\kappa_s (d(x) - l))}{2}. \quad (6)
\]
From Equation (6), we see that SWI encodes scene depth $d(x)$ in the phase $\phi(d(x)) \equiv 2\kappa_s (d(x) - l)$ of the envelope sinusoid. We defer details on how to measure the envelope and estimate this phase until Section 4. We make two observations: First, SWI provides depth measurements at intervals of $[0, \lambda_s/2]$, and cannot disambiguate between depths differing by an integer multiple of $\lambda_s/2$. Second, the use of two wavelengths makes it possible to control the unambiguous depth range: by decreasing the separation $\epsilon$ between the two wavelengths, we increase the unambiguous depth range, at the cost of decreasing depth resolution.

**Full-field and scanning interferometry.** Figure 5 shows two types of Michelson interferometer setups that implement SWI: (a) a full-field interferometer; and (b) a scanning interferometer. We discuss their relative merits, which will motivate our proposed swept-angle interferometer setup.

Full-field interferometers (Figure 5(a)) use free-space optics to illuminate and image the entire field of view in the scene and reference arms. They also use a two-dimensional sensor to measure interference at all locations $x$. This enables fast interference measurements for all scene points at once, at lateral resolutions equal to the sensor pixel pitch.

Unfortunately, full-field interferometers are susceptible to phase corruption effects, as we visualize in Figure 4. Equation (5) assumes that the scene field is due to only the direct light path (solid line in Figure 4(a)), which produces a sinusoidal envelope with phase delay $d(x)$ (solid orange curve in Figure 4(b)). In practice, the scene field will include contributions from additional paths: First, indirect paths due to subsurface scattering (dashed lines in Figure 4(a)). Second, stray paths due to optical aberrations (Figure 4(c)). These paths have different lengths, and thus contribute to the envelope sinusoidal terms of different phases (dashed curves in Figure 4(b)). Their summation produces an overall sinusoidal envelope (black) with phase $d' \neq d(x)$, resulting in incorrect depth estimation.

Scanning interferometers (Figure 5(b)) use fiber optics (couplers, circulators, collimators) to generate a focused beam that illuminates only one point in the scene and reference arms. Additionally, they use a single-pixel sensor, focused at the same point. They also use steering optics (e.g., MEMS mirrors) to scan the focus point and capture interference measurements for the entire scene.

Scanning interferometers effectively mitigate the phase corruption effects in Figure 4: Because, at any given time, they only illuminate and image one point in the scene, they eliminate contributions from indirect paths such as those in Figure 4(a). Additionally, because the use of fiber optics minimizes aberrations, they eliminate stray paths such as those in Figure 4(c). Unfortunately, this robustness comes at the cost of having to use beam steering to scan the entire scene. This translates into long acquisition times, especially when it is necessary to measure depth at pixel-level lateral resolutions and at a sensor-equivalent field of view.

In the next section, we introduce an interferometer design that combines the fast acquisition and high lateral resolution of full-field interferometers, with the robustness to phase corruption effects of scanning interferometers.

### 4. Swept-angle illumination

In this section, we design a new light source for use with full-field SWI, to mitigate the phase corruption effects shown in Figure 4—in direct illumination, aberrations. Figure 5(c) shows our final swept-angle optical design.

**Interferometry with spatially-incoherent illumination.** Our starting point is previous findings on the use of spatially-incoherent illumination in full-field interferometric implementations. Specifically, Gkioulekas et al. [20] showed that using spatially incoherent illumination in a Michelson interferometer is equivalent to direct-only probing: this optically rejects indirect paths and makes the correlation term $\mathcal{C}$ depend predominantly on contributions from direct paths. Additionally, Xiao et al. [72] showed that using spatially-incoherent illumination makes the correlation term $\mathcal{C}$ insensitive to aberrations in the free-space optics.

Both Gkioulekas et al. [20] and Xiao et al. [72] realize spatially-incoherent illumination by replacing the point emitter in Figure 3 with an area emitter, e.g., LED or halogen lamp. Unfortunately, fundamental physics dictate that extending emission area of a light source is coupled with
We can interpret Equation (7) as follows: the image $I$ measured using an area emitter equals the sum of the images that would be measured using independent point emitters spanning the emission area, each producing illumination at an angle $\theta$ (and respectively for correlation $C$).

With this interpretation at hand, we design the setup of Figure 5(c) to emulate a spatially-incoherent source suitable for SWI through time-division multiplexing. We use a galvo mirror to steer a narrow collimated beam of narrow-linewidth dichromatic illumination. We focus this beam through a relay lens at a point on the focal plane of the illumination lens. As we steer the beam direction, the focus point scans an area on the focal plane. In turn, each point location results in the injection of illumination at an angle $\theta$ in the interferometer. By scanning the focus point over a target effective emission area within a single exposure, we acquire image and correlation measurements that equal those of Equation (7). As this design sweeps the illumination angle, we term it swept-angle illumination, and its combination with full-field SWI swept-angle synthetic wavelength interferometry.

**Comparison to Kotwal et al. [41]**. The illumination module of the proposed setup in Figure 5(c) is an adaptation of the Fourier-domain redistributive projector of Kotwal et al. [41]. Compared to their setup, we do not need to use an amplitude electro-optic modulator, as we are only interested in emulating spatial incoherence (equivalent, directly probing). Additionally, their setup was designed for use with monochromatic illumination, to enable different light transport probing capabilities. By contrast, we use our setup with narrow-linewidth dichromatic illumination, to enable synthetic wavelength interferometry. More broadly,
our key insight is that swept-angle illumination can emulate extended-area emitters with arbitrary spectral profiles.

5. The \( \{M, N\} \)-shift phase retrieval algorithm

We discuss our pipeline for acquiring and processing measurements to estimate the envelope phase, and thus depth. For this, in Figure 5(c), we use a nanometer-accuracy stage to vary the position \( l \) of the reference mirror.

**Phase retrieval.** We use the \( N \)-shift phase retrieval algorithm [9, 63, 64] to compute the envelope phase: We assume we have estimates of the envelope’s squared amplitude \( |\mathcal{E}(x, l_n)|^2 \) at reference positions \( l_n \) corresponding to shifts by \( N \)-th fractions of the synthetic half-wavelength \( \lambda_s/2 \), \( n \in \{0, \ldots, N - 1\} \). Then, from Equation (6), we estimate the envelope phase as

\[
\phi(d(x)) = \arctan \left( \frac{\sum_{n=0}^{N-1} |\mathcal{E}(x, l_n)|^2 \sin(2\pi n/N)}{\sum_{n=0}^{N-1} |\mathcal{E}(x, l_n)|^2 \cos(2\pi n/N)} \right),
\]

Equation (8) requires estimates of \( |\mathcal{E}(x, l_n)|^2 \). For each \( l_n \), we capture intensity measurements \( I(x, l_{n}^m) \) at \( M \) reference positions corresponding to shifts by \( M \)-th fractions of the carrier wavelength, \( l_{n}^m = l_n + m\lambda_s/M, m \in \{0, \ldots, M - 1\} \). As the carrier wavelength \( \lambda_s \) is half the optical wavelength \( \lambda \) and orders of magnitude smaller than the synthetic wavelength \( \lambda_s \), the envelope and interference-free image remain approximately constant across shifts, \( \mathcal{E}(x, l_{n}^m) \approx \mathcal{E}(x, l_n), \mathcal{I}(x, l_{n}^m) \approx \mathcal{I}(x, l_n) \). Then, from Equations (1) and (4),

\[
I(x, l_{n}^m) = \mathcal{I}(x, l_n) + 2 \sin(\kappa_n(d(x) - l_{n}^m)) \mathcal{E}(x, l_n).
\]

We estimate the interference-free image and envelope as

\[
\mathcal{I}(x, l_n) = \frac{1}{M} \sum_{m=0}^{M-1} I(x, l_{n}^m), \quad (11)
\]

\[
|\mathcal{E}(x, l_n)|^2 = \frac{1}{2M} \sum_{m=0}^{M-1} (I(x, l_{n}^m) - \mathcal{I}(x, l_n))^2. \quad (12)
\]

Equations (11), (12), (8), and (9) complete our phase estimation pipeline, which we summarize in Figure 6. We note that the runtime of this pipeline is negligible relative to acquisition time. We provide algorithmic details and pseudocode in the supplement. We call this pipeline the \( \{M, N\} \)-shift phase retrieval algorithm. The parameters \( M \) and \( N \) are design parameters that we can fine-tune to control a trade-off between acquisition time and depth accuracy: As we increase \( M \) and \( N \), the number \( M \cdot N \) of images we capture also increases, and depth estimates become more robust to noise. The theoretical minimum number of images is achieved using \( \{3, 3\} \) shifts (9 images). In practice, we found \( \{4, 4\} \) shifts to be robust. We evaluate different \( \{M, N\} \) combinations in the supplement.

**Dealing with speckle.** Interference in non-specular scenes takes the form of speckle, a high-frequency pseudo-random pattern (Figure 6(a)). This can result in noisy envelope, and thus phase and depth, estimates. As Figures 4(d) and 7 show, swept-angle illumination greatly mitigates speckle effects. We can further reduce the impact of speckle by denoising estimated quantities with a low-pass filter (e.g., Gaussian) [20, 41]. Alternatively, to avoid blurring image details, we can use joint bilateral filtering [12, 59] with a guide image of the scene under ambient light. Empirically, we found it better to blur the envelope estimates of Equation (12) before using them in Equation (8) (Figure 6(d)), compared to blurring the phase or depth estimates.

6. Experiments

**Experimental prototype.** For all our experiments, we use the experimental prototype in Figure 5(c). Our prototype comprises: two distributed-Bragg-reflector lasers (wavelengths 780 nm and 781 nm, power 45 mW, linewidth 1 MHz); a galvo mirror pair; a translation stage (resolution 2700 pixels); and a minimum per-image exposure time of 10 ms, resulting at a frame rate of 5 Hz.

**Depth recovery on challenging scenes.** Figures 8 and 2 show scans of many challenging scenes. We scan materials ranging from rough metallic (coins), to diffuse (music box, pill), to highly-scattering (soap and chocolate). Most scenes include fine features requiring high lateral and axial resolution (music box, business card, US quarter, dollar bill). We compare scan results using swept-angle SWI (with bilateral or Gaussian filtering), versus conventional full-field SWI (Figure 5(a), emulated by deactivating the angle-sweep galvo). In all scenes, using swept-angle illumination greatly improves reconstruction quality. The difference is more pronounced in scenes with strong subsurface scattering (music box, chocolate, soap). Even in metallic scenes where there is no subsurface scattering (coins), the use of swept-angle illumination still improves reconstruction quality, by helping mitigate aberration artifacts. Bilateral filtering further improves lateral detail compared to Gaussian filtering.

**Comparison with scanning SWI.** A direct comparison of
swept-angle SWI with scanning SWI is challenging, because of the differences between scanning and full-field setups (Figure 5, (b) versus (a), (c)). To qualitatively assess their relative performance, in Figure 9 we use the following experimental protocol: We downsample the depth map from our technique, by a factor of 35 in each dimension. This is approximately equal to the number of depths points a scanning SWI system operating in point-to-point mode would acquire at the same total exposure time as ours, when equipped with beam-steering optics that operate at a 30 kHz scan rate—we detail the exact calculation in the supplement. We then use joint bilateral upsampling [40] with the same guide image as in our technique, to upsample the downsampled depth map back to its original resolution. We observe that, due to the sparse set of points scanning SWI can acquire, the reconstructions miss fine features such as the hair on the quarter and letters on the business card.

Scanning SWI systems can also operate in resonant mode, typically using Lissajous scanning to raster scan the field of view [47]. Resonant mode enables much faster operation than the point-to-point mode we compare against. However, Lissajous scanning results in non-rectilinear sampling of the image plane, as scan lines smear across multiple image rows (when the fast axis is horizontal). At high magnifications, this produces strong spatial distortions and artifacts, making resonant mode operation unsuitable for applications that require micrometer lateral resolution. Our technique also uses resonant-mode Lissajous scanning, but to raster scan the focal plane of the illumination lens (Figure 5(d)), and not the image plane. Instead, our technique uses a two-dimensional sensor to sample the image plane, thus completely avoiding the artifacts above and achieving micrometer lateral resolution. The supplement discusses other challenges in achieving high lateral resolution with scanning SWI.

Additionally, our technique is orders of magnitude faster than resonant-mode scanning SWI at the same lateral resolution. This is because, whereas scanning SWI must scan the image plane at the target (pixel-level) lateral resolution, our
We then bilaterally upsample it to the original resolution.

In the supplement: 1) Additional experiments. 2) Tunable depth range. 3) Robustness to ambient lighting. We show that the use of near-monochromatic illumination makes swept-angle SWI robust to strong ambient light, even at 10% signal-to-background ratios. 4) Effect of scanning resolution and \( \{M, N\} \) settings. We show that, by adjusting the focal plane scanning resolution and \( \{M, N\} \) parameters for phase retrieval, swept-angle SWI can trade off between acquisition time versus reconstruction quality.

7. Limitations and conclusion

Phase wrapping. SWI determines depth only up to an integer multiple of the synthetic half-wavelength \( \lambda/2 \). Equivalently, all depth values are wrapped to \([0, \lambda/2)\), even if the depth range is greater. To mitigate phase wrapping and extend unambiguous depth range, it is common to capture measurements at multiple synthetic wavelengths, and use them to unwrap the phase estimate [3, 7, 8, 11]. Theoretically two synthetic wavelengths are enough to uniquely determine depth, but in practice phase unwrapping techniques are very sensitive to noise [25]. Combining phase unwrapping with our technique is an interesting future direction.

Toward real-time operation. Our prototype acquires measurements at a frame rate of 5 Hz, due to the need for 10 ms per-frame exposure time. If we use a stronger laser to reduce this time, the main speed bottleneck will be the need to perform phase shifts by physically translating the reference mirror. We can mitigate this bottleneck using faster translation stages (e.g., fast microscopy stages).

Conclusion. We presented a technique for fast depth sensing at micron-scale lateral and axial resolutions. Our technique, swept-angle synthetic wavelength interferometry, combines the complementary advantages of full-field interferometry (speed, pixel-level lateral resolution) and scanning interferometry (robustness to aberrations and indirect illumination). We demonstrated these advantages by scanning multiple scenes with fine geometry and strong subsurface scattering. We expect our results to motivate applications of swept-angle SWI in areas such as biomedical imaging, and industrial fabrication and inspection (Figure 1).

Acknowledgments. We thank Sudershan Boovaraghavan, Yuvraj Agrawal, Arpit Agarwal, Wenzhen Yuan from CMU, and Veniamin V. Stryzhev, Brian T. Miller from The Boeing Company, who provided the samples for the experiments in Figure 1. This work was supported by NSF awards 1730147, 2047341, 2008123 (NSF-BSF 2019758), and a Sloan Research Fellowship for Ioannis Gkioulekas.
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